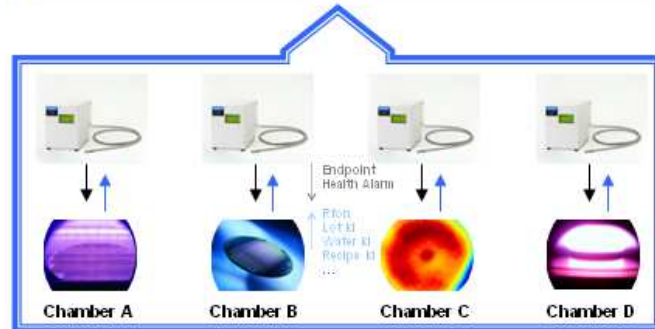
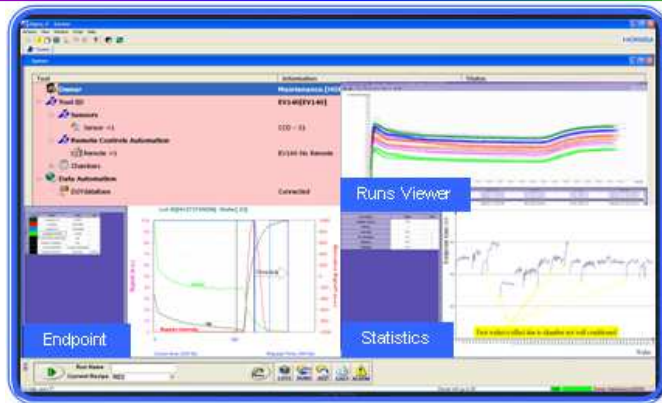


## EV-1000 Supervision

### Endpoint Control on Cluster Tools: Dry Etch, Cleaning, PECVD

200

800 nm



- **Engineering Toolbox for Plasma analysis**
  - Process understanding
  - Process development
- **Production Endpoint Monitoring software**
  - 24/24 Run to run Product monitoring
  - Flexible & confidential recipes
  - Fab's Automation
- **Quality Plug-in, R2R control**
  - Database
  - Statistics
  - Multi-Runs Viewer
- **Maintenance**
  - Stability Health Chamber Monitoring
  - Fault Detection

